

#2  
DKing  
3/13/01

Inventors: Kie Y. Ahn, Leonard Forbes and Jerome Eldridge

Title: Methods of Forming Capacitor Structures, and Capacitor Structures

Assignee: Micron Technology, Inc.

JE675 U.S. PTO  
09/755673  
01/05/01

EL465852887

**INFORMATION DISCLOSURE STATEMENT**

**PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98**

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, the Examiner's attention is directed to the references listed on the attached Form PTO-1449 and copies of which are attached. No admission is made regarding whether all the submitted references are prior art.

Citation of these references are respectfully requested.

**INVENTORS:**

Date: \_\_\_\_\_

Leonard Forbes

Date: \_\_\_\_\_

Kie Y. Ahn

Date: \_\_\_\_\_

Jerome Michael Eldridge

Respectfully submitted,

Date: 11/5/01

Attorney: \_\_\_\_\_

David G. Latwesen, Ph.D.  
Reg. No. 38,533  
Wells, St. John, Roberts,  
Gregory & Matkin, P.S.

Inventors: Kie Y. Ahn, Leonard Forbes and Jerome Eldridge

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**INVENTORS:**

Date: \_\_\_\_\_

\_\_\_\_\_  
Leonard Forbes

Date: Dec. 28, 2000

Kie Y. Ahn  
Kie Y. Ahn

Date: \_\_\_\_\_

\_\_\_\_\_  
Jerome Michael Eldridge

Respectfully submitted,

Date: \_\_\_\_\_

Attorney: \_\_\_\_\_

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Date: \_\_\_\_\_

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Leonard Forbes

Date: \_\_\_\_\_

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Kie Y. Ahn

Date: 12/28/2000

Jerome Michael Eldridge  
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Respectfully submitted,

Date: \_\_\_\_\_

Attorney: \_\_\_\_\_

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**INVENTORS:**

Date: 27 Dec 2000

  
Leonard Forbes

Date: \_\_\_\_\_

\_\_\_\_\_  
Kie Y. Ahn

Date: \_\_\_\_\_

\_\_\_\_\_  
Jerome Michael Eldridge

Respectfully submitted,

Date: \_\_\_\_\_

Attorney: \_\_\_\_\_

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